

## Product Comparison

	<b>IST RPX-540, -560</b>	Competition (a Vapor Prime Oven)
<b>Equipment Size:</b>	27"x39"x76"	~46"x39"x45"
<b>Chamber Dimension:</b>	12"x20"x16" (-540) 16"x20"x17" (-560)	~ 16"x18"x16"
<b>Chamber Material / Construction:</b>	Structural T6061 Aluminum 100% Corrosion Proof	Welded 304 Stainless Steel
<b>Temperature Uniformity:</b>	± 10C	± 30C
<b>Chamber Temperature:</b>	RT to 1400C	~ near 2000C
<b>Chamber Pressure Control:</b>	10mt - 10Torr	100mt - 100Torr
<b>Chemical Dispense:</b>	Vaporization or Carrier Gas Assist metered by MFC	Mechanical Displacement Pump
<b>Chemical Control Capability:</b>	Partial Pressure control by capacitance manometer	Liquid Dispense Volume onto a Hot Plate
<b>Precursors Capability:</b>	Configurable from 1 to 5 precursors with Interchangeable Cartridges + 1 Gas Source  Cartridges are RF-ID tagged for complete chemical traceability.	Up to 3 precursor bottles
<b>Process Capability:</b>	Silane & Metal Organics for ALD	Silanes
<b>RF Plasma:</b>	40kHz - 1000 Watts or 13.56MHz @ 600Watts or 13.56MHz (Pulse) @ 1000Watts	40KHz - 1000Watts
<b>Loading Configurations:</b>	Multi-Shelves, Wafer cassettes up to 300mm	Multi-Shelves, Wafer cassettes up to 300mm
<b>Software / Control:</b>	Windows-11 OS + Labview® Graphic Interface.  Internet enabled. Remote monitoring and control available from anywhere in the world.	PLC
<b># of Process Recipes:</b>	Only limited by disk space	up to 6
<b>Power Requirements:</b>	208V - 230VAC	208V - 230VAC